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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/510,152	10/05/2004	Kia Silverbrook	YU175NPUS	6673
24011 7590 09/17/2008 SILVERBROOK RESEARCH PTY LTD 393 DARLING STREET			EXAMINER	
			AL HASHIMI, SARAH	
BALMAIN, 2041 AUSTRALIA			ART UNIT	PAPER NUMBER
			2853	
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Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

	Application No.	Applicant(s)
	10/510,152	SILVERBROOK, KIA
Office Action Summary	Examiner	Art Unit
	Sarah Al-Hashimi	2853
The MAILING DATE of this communication ap Period for Reply	ppears on the cover sheet with the	correspondence address
A SHORTENED STATUTORY PERIOD FOR REPL WHICHEVER IS LONGER, FROM THE MAILING ID. - Extensions of time may be available under the provisions of 37 CFR 1 after SIX (6) MONTHS from the mailing date of this communication. - If NO period for reply is specified above, the maximum statutorior. - Failure to reply within the set or extended period for reply will, by stature Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	DATE OF THIS COMMUNICATIO .136(a). In no event, however, may a reply be tind d will apply and will expire SIX (6) MONTHS from te, cause the application to become ABANDONE	N. mely filed the mailing date of this communication. ED (35 U.S.C. § 133).
Status		
Responsive to communication(s) filed on 10 € This action is FINAL . 2b) ☐ This action is FINAL . Since this application is in condition for allowatelessed in accordance with the practice under	is action is non-final. ance except for formal matters, pr	
Disposition of Claims		
4) Claim(s) 1 and 3-10 is/are pending in the app 4a) Of the above claim(s) 7-9 is/are withdrawr 5) Claim(s) is/are allowed. 6) Claim(s) 1,3-6,10 is/are rejected. 7) Claim(s) is/are objected to. 8) Claim(s) are subject to restriction and/	n from consideration.	
9) The specification is objected to by the Examin 10) The drawing(s) filed on is/are: a) ac Applicant may not request that any objection to the Replacement drawing sheet(s) including the correct 11) The oath or declaration is objected to by the E	cepted or b) objected to by the edrawing(s) be held in abeyance. Section is required if the drawing(s) is ob	e 37 CFR 1.85(a). ojected to. See 37 CFR 1.121(d).
Priority under 35 U.S.C. § 119		
12) Acknowledgment is made of a claim for foreig a) All b) Some * c) None of: 1. Certified copies of the priority documer 2. Certified copies of the priority documer 3. Copies of the certified copies of the priority application from the International Burea * See the attached detailed Office action for a list	nts have been received. nts have been received in Applicat ority documents have been receiv au (PCT Rule 17.2(a)).	ion No ed in this National Stage
Attachment(s) 1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO/SB/08) Paper No(s)/Mail Date	4) Interview Summary Paper No(s)/Mail D 5) Notice of Informal I 6) Other:	ate

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DETAILED ACTION

Claim Rejections - 35 USC § 103

- 1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 2. Claim 1,3-6,10 are rejected under 35 U.S.C. 103(a) as being unpatentable over Fuji (US 6,371,598) in view of Silverbrook (US 6,227,654).

Fujii teaches:

Claim 1: a substrate (fig 16 #1002); and a plurality of nozzle arrangements that is positioned on the substrate (fig 16 #1021), each nozzle arrangement comprising a nozzle chamber structure that is positioned on the substrate and that defines a nozzle chamber from which ink is to be ejected (fig 16 #1006); an ink-ejecting mechanism that is operatively arranged with respect to the nozzle chamber structure, the ink-ejecting mechanism including at least one moving component that is displaceable to generate a pressure pulse within the nozzle chamber to eject ink from the nozzle chamber (fig 16 #1005); an actuator that is positioned on the substrate and that has at least one working member that is of a material having a coefficient of thermal expansion such that the, or each, working member is capable of substantially rectilinear expansion and contraction when heated and subsequently cooled (col 14 lines 22-24 "the pressure generating means may alternatively comprise a resistance heating element disposed in

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ejection chamber 6"); and an energy transmitting means that interconnects the, or each, moving component and the, or each, working member so that energy generated by the, or each, working member as a result of expansion and subsequent contraction of the, or each, working member is transmitted to the, or each, moving component resulting in displacement of the, or each, moving component and generation of said pressure pulse (col 14 lines 18-26 "it is also possible to provide a piezoelectric element as the pressure generating means on the side of diaphragm 5 opposite ejection chamber 6. In this case an appropriate voltage is applied to the piezoelectric device to deform the diaphragm. The pressure generating means may alternatively comprise a resistance heating element disposed in ejection chamber 6 such that the pressure ejecting the ink is created by the thermal expansion of the ink induced by the resistance heating element"), wherein, in each nozzle arrangement, the ink ejection port is arranged in the nozzle chamber so as to be a distal end portion of the moving component with respect to the working member and energy transmitting means (fig 16 #1021 is at a distal end).

Claim 10: at least one printhead integrated circuit as claimed in claim 1 (fig 1 #10). Fujii does not teach but Silverbrook teaches:

Claim 1: each actuator includes one elongate working arm that has a fixed end portion and a working end portion, the working arm being configured to define part of a resistive heating circuit (abs "actuator having a first conductive arm and a second substantially non-conductive arm, the conductive arm expanding upon electrical resistive heating to thereby cause the actuation of the thermal actuator").

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Claim 3: the substrate includes a silicon wafer substrate (fig 3 #4) and a CMOS drive circuit layer positioned on the silicon wafer substrate (fig 3 #17).

Claim 4: the working arm is also electrically connected to the drive circuitry layer so that a current pulse can be set up in the working arm to displace the working end portion relative to the fixed end portion upon heating and subsequent cooling of the working arm as a result of the current pulse (col 6 lines 24-28 "The expansion works against the nitride portion 12 of the arm resulting in a partial "uncoiling" of the actuator 7 which in turn results in a corresponding movement of the paddle 6 resulting in the ejection of ink from the nozzle chamber 2").

Claim 5: each nozzle chamber structure includes nozzle chamber walls and a roof positioned on the nozzle chamber walls, the roof defining the ink ejection port from which ink is ejected upon generation of said pressure pulse (abs "a trough having side walls and an exposed roof the trough being substantially filled with fluid; a paddle vane located within the trough and offset from one wall when the paddle vane is in a quiescent position; an actuation mechanism attached to the paddle vane such that, upon activation of the actuation mechanism, the paddle vane is caused to move towards the one wall, resulting in an increase in pressure in the fluid between the one wall and the paddle vane, resulting in a consequential ejection of fluid via the exposed roof").

Claim 6: each ink-ejecting mechanism includes one moving component in the form of an ink-ejecting member that is positioned in the nozzle chamber and is displaceable towards and away from the roof to generate said pressure pulse (abs "an actuation")

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mechanism attached to the paddle vane such that, upon activation of the actuation mechanism, the paddle vane is caused to move towards the one wall, resulting in an increase in pressure in the fluid between the one wall and the paddle vane, resulting in a consequential ejection of fluid via the exposed roof").

Therefore it would have been obvious to a person having ordinary skill in the art at the time the invention was made to modify Fujii to incorporate each actuator includes one elongate working arm that has a fixed end portion and a working end portion, the working arm being configured to define part of a resistive heating circuit, the working arm is also electrically connected to the drive circuitry layer so that a current pulse can be set up in the working arm to displace the working end portion relative to the fixed end portion upon heating and subsequent cooling of the working arm as a result of the current pulse, each nozzle chamber structure includes nozzle chamber walls and a roof positioned on the nozzle chamber walls, the roof defining the ink ejection port from which ink is ejected upon generation of said pressure pulse, each ink-ejecting mechanism includes one moving component in the form of an ink-ejecting member that is positioned in the nozzle chamber and is displaceable towards and away from the roof to generate said pressure pulse and the substrate includes a silicon wafer substrate (fig. 3 #4) and a CMOS drive circuit layer positioned on the silicon wafer substrate as taught by Silverbrook to reduce manufacturing costs and improve print function.

Response to Arguments

3. Applicant's arguments with respect to claims 1,3-6,10 have been considered but are most in view of the new ground(s) of rejection.

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Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Sarah Al-Hashimi whose telephone number is 571 272 7159. The examiner can normally be reached on M-F.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Stephen Meier can be reached on 571 272 2149. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either PAIR or Public PAIR. Status information for unpublished applications is available through PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/SA/

/STEPHEN D. MEIER/ Supervisory Patent Examiner, Art Unit 2853